

SOL-GEL SILICA

**Properties, Processing and
Technology Transfer**



by
Larry L. Hench

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NOYES PUBLICATIONS
Westwood, New Jersey, U.S.A.

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Library of Congress Catalog Card Number: 98-19933

ISBN: 0-8155-1419-0

Printed in the United States

Published in the United States of America by

Noyes Publications

369 Fairview Avenue, Westwood, New Jersey 07675

10 9 8 7 6 5 4 3 2 1

Library of Congress Cataloging-in-Publication Data

Hench, L. L.

Sol-gel silica : properties, processing, and technology transfer /
by Larry L. Hench.

p. cm.

Includes bibliographical references and index.

ISBN 0-8155-1419-0

1. Ceramic materials. 2. Colloids. I. Title.

TP810.5.H45 1998

620.1'4--dc21

98-19933

CIP

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Preface

This book summarizes fifteen years of research in sol-gel processing of silica leading to the commercial development of gel-silica optics and bioactive gel-glasses for medical applications. Each of the seven stages of sol-gel processing is described with emphasis on control of the ultrastructural variables necessary to make reproducible materials. A unique feature of the book is its emphasis on the practical outcome of the processing studies, i.e., commercially viable production of net shape, net surface, and monolithic optical components. It is shown that reliable drying of gel-silica optics requires control of gel texture, especially the distribution of pore sizes, which is a function of the kinetics of hydrolysis and condensation reactions occurring during mixing and gelation, and also the kinetics and environment of the cast component.

The environmental stability of porous gel monoliths is of special concern in the book because it can limit the utility of porous optical matrices, Type VI gel-silica, and also severely restrict the ability to transform porous gel into a fully dense silica optical component, Type V gel silica. The book shows how theory and experiment are combined to solve the problem of environmental stabilization; semi-empirical quantum mechanical calculations provide insight as to the mechanism of water attack of surface defects within the interconnected pore network. Experiments are described which determined the concentration of surface defects, the dimensions of the hydrated layers within the network and the specific thermochemical treatments required to stabilize the surface of the pores without collapsing them.

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The ability to make stable porous matrices with interconnected porosity of controllable size makes it possible to impregnate the pores with optically active second phases. The processing and properties these new generations of optical composites are described in the book with numerous examples from published papers and Ph.D. theses. The production of fully dense optical silica components is also presented along with many advantages including: improved physical properties and net shape, net surface processing of microlenses, surface diffractive optics, aspheres, micro-optical arrays, and laser written waveguides.

Addition of CaO and P_2O_5 to the silica precursor during mixing leads to a new material, a biologically active gel-glass which enhances the repair and regeneration of bone. A chapter reviews the concept of bioactive implant materials and the important advances associated with sol-gel processing of bioactive glasses.

A final chapter addresses one of the most difficult topics of all: how to make the transfer of technology from the laboratory to a profitable commercial enterprise. Principles of technology transfer are presented and the separate pathways involved in moving from a research program to pilot plant are discussed using examples from various chapters in the book. Thus, this book presents an unique perspective of twentieth century research and development in materials science. It starts with the concept of using ultrastructure processing to produce a new generation of optical and medical materials and shows step by step the sequence of experiments conducted to reduce the concept to a commercial reality.

London, England
February, 1998

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